

PATENT ASSIGNMENT

Electronic Version v1.1
 Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
Planar Systems, Inc.	02/08/2008
RECEIVING PARTY DATA	
Name:	Lotus Applied Technology, LLC
Street Address:	1050 NW Compton Drive
City:	Hillsboro
State/Country:	OREGON
Postal Code:	97006
PROPERTY NUMBERS Total: 5	
Property Type	Number
Application Number:	11691421
PCT Number:	US0764961
Application Number:	11829050
PCT Number:	US0774521
Application Number:	60889492
CORRESPONDENCE DATA	
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<i>Correspondence will be sent via US Mail when the fax attempt is unsuccessful.</i>	
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ATTORNEY DOCKET NUMBER:	39559-1
NAME OF SUBMITTER:	Kassim M. Ferris

OP \$200.00 11691421

PATENT

Total Attachments: 3

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Patent Assignment

WHEREAS, Planar Systems, Inc., an Oregon corporation ("Assignor"), desires to sell, transfer, convey, assign, and deliver all of its right, title, and interest in and to the patent applications listed on Annex A hereto together with the inventions described therein (the "Assigned Intellectual Property"); and

WHEREAS, Lotus Applied Technology, LLC, an Oregon limited liability company ("Assignee"), desires to acquire all of Assignor's right, title, and interest in and to the Assigned Intellectual Property;

NOW, THEREFORE, for good and valuable consideration, the receipt and adequacy of which are hereby acknowledged by Assignor, Assignor does hereby sell, transfer, convey, assign, and deliver to Assignee all of Assignor's right, title, and interest in and to the Assigned Intellectual Property, including any and all patent rights and letters patent for said inventions in the United States of America and elsewhere throughout the world, including provisional rights, foreign patent priority rights, and the right to apply for patents in foreign countries in the name of Assignee, and further including all divisions and continuations of said application and of any foreign patent applications, and all reissues and extensions of patent rights and letters patent for said inventions, all to be held and enjoyed by Assignee, for its own use and benefit, and by its successors and assigns for their own use and benefit, for the full duration of the terms for which patent rights and letters patent may be granted in this or any foreign country, and further with all rights of action, powers and benefit to the Assigned Intellectual Property, due or accrued, including the right to sue for and recover in the Assignee's own name and that of its successors and assigns and other legal representatives all remedies of every nature, including, without limitation, rights to injunctive relief, damages, profits, costs and attorney fees, arising out of past infringement of the Assigned Intellectual Property.

This Patent Assignment shall inure to the benefit of and be binding upon Assignee and Assignor and their respective successors and assigns.

[SIGNATURE PAGE FOLLOWS]

IN WITNESS WHEREOF, Assignor has executed this Patent Assignment as of February 8, 2008.

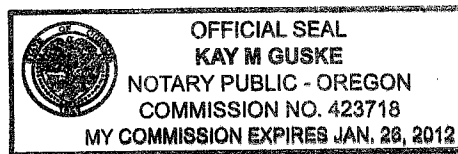
PLANAR SYSTEMS, INC.

By: *Stephen M. Going*
Stephen M. Going
Vice President, General Counsel & Secretary

State of Oregon)
) ss.
County of Washington)

This instrument was acknowledged before me on February 8, 2008 by Stephen M. Going.

Kay M. Guske
Notary Public for Oregon
My Commission Expires: 01/26/2012



ANNEX A

Intellectual Property

Patent Application Number	Filing Date	Title
U.S. App. No. 11/691,421	3/26/2007	ATOMIC LAYER DEPOSITION SYSTEM AND METHOD FOR COATING FLEXIBLE SUBSTRATES
PCT App. No. PCT/US2007/64961	3/26/2007	ATOMIC LAYER DEPOSITION SYSTEM AND METHOD FOR COATING FLEXIBLE SUBSTRATES
U.S. App. No. 11/829,050	7/26/2007	RADICAL-ENHANCED ATOMIC LAYER DEPOSITION SYSTEM AND METHOD
PCT App. No. PCT/US2007/74521	7/26/2007	RADICAL-ENHANCED ATOMIC LAYER DEPOSITION SYSTEM AND METHOD
U.S. Provisional App. No. 60/889,492	2/12/2007	FABRICATION OF COMPOSITE MATERIALS USING ATOMIC LAYER DEPOSITION